

EXAMINER'S AMENDMENT

1. An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it **MUST** be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with Lee Stepina on 6/11/2009.

The application has been amended as follows: Claim 1 is amended as follows.
Delete previous version of claim 1 and replace with the following:

Claim 1: A semiconductor device manufacturing method using a plasma processor, wherein said plasma processor includes:

a vacuum processing chamber in which plasma is generated to plasma-process an object to be processed;

a block having a flow path of a heat medium in an inner part thereof; and

a component in the vacuum processing chamber disposed to be in contact with the block and made at least partly of an insulative material, and

wherein said plasma processor controls a temperature of the component in the vacuum processing chamber by circulating an insulating fluid as the heat medium in the flow path, and

said method comprising:

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carrying the object to be processed into the vacuum processing chamber, generating plasma to plasma-process the object to be processed, and carrying the object to be processed that has undergone the processing out of the vacuum processing chamber;

between said processing of the object to be processed and processing of a subsequent object to be processed, circulating the insulating fluid in the flow path while the object to be processed is not in the vacuum processing chamber and no plasma is generated, and controlling pressure in the vacuum processing chamber to a predetermined pressure while supplying inert gas as a purging gas into the vacuum processing chamber; and

determining and applying a pressure of said inert gas on a Paschen's curve so that electrical charging of the component in the vacuum processing chamber is suppressed.

Allowable Subject Matter

1. Claims 1-7, 9-11, 23, are allowed.
2. The examiner's statement of reasons for allowance has been provided in the office action issued on 2/24/2009.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably

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accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to MAHMOUD DAHIMENE whose telephone number is (571)272-2410. The examiner can normally be reached on week days from 8:00 AM. to 5:00 PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nadine Norton can be reached on (571) 272-1465. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

/M. D./
Examiner, Art Unit 1792

/Nadine G Norton/
Supervisory Patent Examiner, Art Unit 1792

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